

INFORMATION DISCLOSURE CITATION	ATTY. DOCKET NO. 249-245	SERIAL NO. 10/053576
(Use several sheets if necessary)	APPLICANT TOMONARI et al.	Unknown
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## U.S. PATENT DOCUMENTS

EXAMINER INITIAL	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
DNY	5,058,856	10/1991	GORDON et al.	251	11	
pmj	5,069,419	12/1991	JERMAN	251	11	
pmj	5,271,597	12/1993	JERMAN	251	11	
TMY	5,059,133	10/1991	HIKAMI et al.	439	16	
pmj	5,870,007	2/1999	CARR et al.	333	262	
TMY	5,920,417	7/1999	JOHNSON	359	223	
pmj	6,044,646	4/2000	SILVERBROOK	60	528	
pmj	6,114,794	9/2000	DHULER et al.	310	307	
pmj	1,258,368	3/1918	SMITH	194	283	
TMY	4,115,750	9/1978	HANSEN et al.	337	107	
TMY	6,087,638	7/2000	SILVERBROOK	214	540	
pmj	6,124,663	9/2000	HAAKE et al.	310	307	

## FOREIGN PATENT DOCUMENTS

	DOCUMENT	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION YES	TRANSLATION NO
TMO	9-88805	3/1997	JAPAN	F03G	7/06		
TMO	10-173306	6/1998	JAPAN	H05K	1/14	✓	

## OTHER DOCUMENTS (including Author, Title, Date, Pertinent pages, etc.)

DNY	"Silicon Microvalves for Gas Flow Control" Phillip W. Barth, Ph.D. Hewlett-Packard Laboratories pp 276-279 The 8 <sup>th</sup> International Conference on Solid-State Sensors and Actuators, and Eurosensors IX. Stockholm, Sweden, June 25-29, 1995 (in parent case 09/511,948, now USP 6,384,509)
TMY	"Electrically-Activated, Micromachined Diaphragm Valves" Hal Jerman IC Sensors Milpitas, CA 95035 pp 363-367 (in parent case 09/511,948, now USP 6,384,509)

Examiner*	Date Considered
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\*Examiner: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to application.

Form PTO-FB-A620 (Also PTO-1449)